

# INFORMATION DISCLOSURE CITATION IN AN APPLICATION

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SERIAL NO.

APPLICANT  
**Hong-Da LIU**

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GROUP

1c978 U.S. PRO  
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## U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
T.R.C.	3,930,857	1/6/1976	Bendz et al.	430	313	
	5,111,240	5/5/1992	Boetiger et al.	355	53	
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	5,648,860	7/15/1997	Ooi et al.	349	10	
	5,777,713	7/7/1998	Kimura	349	156	
	5,978,062	11/2/1999	Liang et al.	349	155	
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## FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

T.R.C.	K. Ismail, "A novel method for submicron structuring using optical projection lithography", Microelectronic Engineering Vol.1, No. 4, pp. 295-300 (1983).
	M.J. Cole et al., "Moving fiber/phase mask-scanning beam technique for enhanced flexibility in producing fibre gratings with uniform phase mask", Electronic Letter, 17th Aug. 1995, Vol. 31, No. 17, pp. 1488-1490 (1995).
	O. Tabata et al., "Moving mask Liga (M <sup>2</sup> LIA) process for control of side wall inclination", Micro-Electro Mechanical System, 1999, MEMS 1999, The 12 <sup>th</sup> IEEE International Conference, pp. 252-256 (1999).
EXAMINER	DATE CONSIDERED 09/25/03

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.